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Application No.	10/047,550	Prepared by	B2M	Tracking Number	05931458
Examiner-GAU	Fiorilla - 1731	Date	4-27-04	Week Date	04/05/04
		No. of queries	2		IFW

**JACKET**

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|----------------------|------------------------|--------------------|--|
| a. Serial No.        | f. Foreign Priority    | k. Print Claim(s)  | <input checked="" type="checkbox"/> PTO-1449 |
| b. Applicant(s)      | g. Disclaimer          | l. Print Fig.      | <input type="checkbox"/> q. PTOL-85b         |
| c. Continuing Data   | h. Microfiche Appendix | m. Searched Column | <input type="checkbox"/> r. Abstract         |
| d. PCT               | i. Title               | n. PTO-270/328     | <input type="checkbox"/> s. Sheets/Figs      |
| e. Domestic Priority | j. Claims Allowed      | o. PTO-892         | <input type="checkbox"/> t. Other            |

- SPECIFICATION**
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  - g. Brief Description
  - h. Sequence Listing
  - i. Appendix
  - j. Amendments
  - k. Other

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attached. (7 pages)  
⑥) Claim #7 is missing the period.  
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**RESPONSE** \_\_\_\_\_

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FORM PTO-1449  
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JUL 14 2003

U.S. Department of Commerce  
Patent and Trademark OfficeINFORMATION DISCLOSURE STATEMENT BY APPLICANT  
(Use Several Sheets If Necessary)

(37 CFR § 1.98(b))

Attorney Docket No.: SLM-06100

Serial No.: 10/047,550

Applicants: Gregory D. Miller et al

Filing Date: January 15, 2002

Group Art Unit: 2881

## U.S. PATENT DOCUMENTS

Examiner Initials		Serial / Patent Number	Issue Date	Applicant / Patentee	Class	Subclass	Filing Date
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	AD	Re. 16,767	10/11/27	Jenkins			10/31/22
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	AG						
	AH						
	AI						

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FORM PTO-1449 (Modified)	JUL 14 2003	U.S. Department of Commerce Patent and Trademark Office	Attorney Docket No.: SLM-06100	Serial No.: 10/047,550
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use Several Sheets If Necessary) (37 CFR § 1.98(b))			Applicants: Gregory D. Miller et al	
			Filing Date: January 15, 2002	Group Art Unit: 2881

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						Yes	No
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	DR	WO 01/57581 A3	08/09/01	WO	G02B	27/48		X

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(37 CFR § 1.98(b))				Filing Date: January 15, 2002	Group Art Unit: 2881

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		Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation
							Yes      No
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U.S. Department of Commerce  
Patent and Trademark Office

Attorney Docket No.: SLM-06100

Serial No.: 10/041450

INFORMATION DISCLOSURE STATEMENT BY APPLICANT  
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(37 CFR § 1.98(b))

Applicants: Gregory D.Miller et al

Filing Date: January 15, 2002

Group Art Unit: 288

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary) (37 CFR § 1.98(b))			Applicants: Gregory D. Miller et al		
			Filing Date: January 15, 2002	Group Art Unit: 2881	
OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)					
	GY	R.W. Corrigan et al. "Calibration of a Scanned Linear Grating Light-Valve, Projection System for E-Cinema Applications", Silicon Light Machines, SID'99, San Jose, CA, 27 pgs, 1999.			
	GZ	R.W. Corrigan et al., "Calibration of a Scanned Linear Grating Light-Valve, Projection System", Silicon Light Machines, San Jose, CA, 4 pgs, May 18, 1999.			
	HA	"Introduction to Cryptography", <a href="http://www.ssh.fi/tech/crypto/intro.html">http://www.ssh.fi/tech/crypto/intro.html</a> , 35 pgs, June 21, 1999.			
	HB	"Deep Sky Black," Equinox InterScience, <a href="http://www.eisci.com/deepsky.html">www.eisci.com/deepsky.html</a> , 1997.			
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